

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Dipankar Chandra, et al.
Filing Date: November 13, 2001
Title: SENSOR FOR DETECTING SMALL
CONCENTRATIONS OF A TARGET MATTER

Assistant Commissioner
For Patents and Trademarks
Washington, DC 20231


Dear Sir:

INFORMATION DISCLOSURE STATEMENT

Applicants respectfully request, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the references listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. Copies of these references are enclosed for the convenience of the Examiner. Furthermore, pursuant to 37 C.F.R. § 1.97(g) and (h), no representation is made that these references are material to patentability of the present application or that a search has been made.

Respectfully submitted,

BAKER BOTTS L.L.P.
Attorneys for Applicants



Brian W. Oaks
Reg. No. 44,981

2001 Ross Avenue
Dallas, Texas 75201-2980
(214) 953-6986

Date: 11/13/01



Handwritten notes:
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CA
2/20/02

PTO-1449	Application No.	Applicant(s) Dipankar (nmi) Chandra, et al.	
	Docket Number 004578.1148	Group Art Unit	Filing Date

 19971 U.S. PTO
10/006891

11/13/01

U.S. PATENT DOCUMENTS

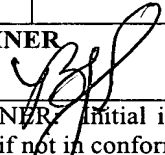
		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	A	4,549,427	10/29/85	Kolesar, Jr.	73	23	9/19/83
	B	4,809,552	3/7/89	Johnson	73	517	11/23/87
	C	4,899,125	26/90	Kurtz	338	2	7/24/87
	D	4,951,510	8/28/90	Holm-Kennedy, et al.	73	862.04	7/14/88
	E	5,028,394	7/2/91	Lowell, Jr., et al.	422	58	4/13/90
	F	5,417,100	5/23/95	Miller, et al.	73	31.02	3/10/93
	G	5,512,882	4/30/96	Stetter, et al.	340	632	8/7/91
	H	5,559,358	9/24/96	Burns, et al.	257	431	5/23/94
	J	5,563,341	10/8/96	Fenner, et al.	73	335.11	6/7/95
	K	5,583,286	12/10/96	Matsuyama	73	105	8/14/95
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							YES	NO
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	P	9705824A	2/10/97	PCT	A61B	5/087		
	Q	445508A2	9/11/91	EP	G01P	13/02		
	R	2244659	3/21/74	DE	F02D	5/00	X	
	S	60250259	10/12/85	EPO - Abstract				
	T	9428372	12/8/94	PCT	G01B	7/16	X	
	U	0821228A1	1/28/98	EP	G01N	27/12		

NON-PATENT DOCUMENTS

		DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
	V	International Search Report for PCT/US99/30540	8/9/00
	W	International Search Report for PCT/US99/30661	4/17/00
	X	T. Nishimoto, S. Shoji and M. Esashi, "Buried piezoresistive sensors by means of MeV Ion Implantation" Sensors and Actuators A, CH, Elsevier Sequoia, S.A., Lausanne, Vol. A43, No. 1/03, pages 249-253, XP000454110	5/1/94
	Y	L. N. Krause, et al., "Miniature Drag-Force Anemometer" I.S.A. Transactions, Vol. 21, No. 1, 1982, pages 37-44, XP002134780	1/1/82
	Z	S. M. Sze, "Semiconductor Sensors" a Wiley-Interscience Publication, pp 193-194, 358-361	1994
	AA	A. J. Ricco, G. C. Osbourn, R. M. Crooks, JW. Bartholomew, C. Xu and R.E. Allred "Interfacial Design and Chemical Sensing" Eds: T. E. Mallouk, D. J. Harrison, p. 264, ACS, Washington DC	1994

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EXAMINER 		DATE CONSIDERED 9/29/2003
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.		

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